## Graded Base / GaAsSb O.5µm Polycrystal Dry Etch Metal 3 Metal 2

Goals, Objectives and Main Technical Approach

Super-scaled InP HBT device development at UIUC and transition to Vitesse of planar 0.25mm HBTs along with 4 level copper interconnect results in an optimal, high yield, manufacturable process with  $F_t$  and  $F_{max}$  exceeding 400 GHz, and Flip-Flop performance of 200 GHz exceeding that of any other competing technology. Techniques developed by the silicon industry

## Major Technical Accomplishments (since start of contract)

- Validated transistor design approach
- 0.45 um transistors operating
- Started topology reduction experiment
- Significant design kit progress
- Started fab of GaAsSb transistor

## Major Work Remaining to Completion of Contract

- Develop 0.25 um transistors with multi level interconnect
- Develop 150GHz FF
- Develop DDS application circuit

Major Impact of Technology & Technology Transition Plan Enables a revolutionary combination of:

- Ultra-high speed performance
- High integration levels
- Low power dissipation
- High Linearity

In one integrated circuit that is well suited for a future generation of miniaturized, agile, RF transceiver applications incorporating high performance DDS circuits. Transistor development aimed at commercialization by Vitesse from the start using 6" copper process.